

### REMARKS

Claims 43-47, 49-51, 53, 54 and 58-65 remain pending in the application.


This Request for Continued Examination (RCE) application is submitted in an abundance of caution simply to place references before the Examiner for consideration. The references are referred to in the Information Disclosure Statement presented herewith.

Also enclosed is a **copy** of the Supplemental Information Disclosure Statement and PTO-1449 which was filed by Express Mail on September 17, 2004. Applicant has never received an initialed copy of this PTO-1449 and respectfully requests the Examiner to initial these references and return a copy of this PTO-1449 with the Examiner's next Action.

Examination of claims 43-47, 49-51, 53, 54 and 58-65 is requested.

Respectfully submitted,

Dated: 12/14/04

By:   
David G. Latwesen, Ph.D.  
Reg. No. 38,533  
Wells St. John P.S.

*Encl.: Copy of 9/17/04 Supp. IDS w/PTO-1449 for initialing*



~~EV372167809~~  
**EV372471047**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application Serial No. .... 10/086,942  
Filing Date ..... March 1, 2002  
Inventor ..... Cem Basceri  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... Y.B. Huynh  
Attorney's Docket No. .... MI22-1951  
Title: Capacitor Constructions Comprising Perovskite-Type Dielectric Materials  
and Having Differnt Degrees of Crystallinity Within the Perovskite-Type Dielectric  
Materials

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449.

The citations listed may be material to the examination of the subject application and are therefore submitted in compliance with the duty of disclosure defined in 37 CFR '1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art. The Examiner is requested to make these citations of official record in this application.

**COPY**

EV372471047

A check in the amount of \$180.00 is enclosed to cover the fee specified  
under 37 C.F.R. § 1.17(p).

Respectfully submitted,

Dated:

9/17/04

By:

David G. Latwesen, Ph.D.  
Reg. No. 38,533

**COPY**

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
M122-1951SERIAL NO.  
10/086,942LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
Cem BasceriFILING DATE  
March 1, 2002GROUP  
2813

DEC 14 2004

## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,261,698	04/81	Carr et al.			
	AB	4,691,662	09/87	Roppel et al.			
	AC	5,261,961	11/93	Takasu et al.			
	AD	5,270,241	12/93	Dennison et al.			
	AE	5,312,783	05/94	Takasaki et al.			
	AF	5,392,189	02/95	Fazan et al.			
	AG	5,395,771	03/95	Nakato			
	AH	5,468,687	11/95	Carl et al.			
	AI	5,525,156	06/96	Manada et al.			
	AJ	5,614,018	03/97	Azuma et al.			
	AK	5,656,329	08/97	Hampden-Smith			
	AL	5,663,089	09/97	Tomozawa et al.			

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM	EP 0 030 798	06/81	EPO - Hughes			N/A	
	AN	GB 2 194 555 A	03/88	UK - Nippon			N/A	
	AO	EP 0 306 069 A2	03/89	EPO - Phillips			N/A	
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR	Aoyama et al., "Leakage Current Mechanism of Amorphous and Polycrystalline Ta <sub>2</sub> O <sub>5</sub> Films Grown by chemical Vapor Deposition," 1995, pages 977-983.
	AS	Stemmer et al., "Accommodation of nonstoichiometry in (100) fiber-textured ... thin films grown by chemical vapor deposition," ©1999 American Institute of Physics, pages 2432-2434.
	AT	Streiffer et al., "Ferroelectricity in thin films: The dielectric response of fiber-textured ... thin films grown by chemical vapor deposition," ©1999 American Institute of Physics, pages 4564-4575.

EXAMINERs

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

COPY

Form PTO-449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
M122-1951SERIAL NO.  
10/086,942

DEC 14 2004

LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
Cem BasceriFILING DATE  
March 1, 2002GROUP  
2813

## U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	5,702,562	12/97	Wakahara			
AB	5,719,417	02/98	Roeder et al.			
AC	5,723,361	03/98	Azuma et al.			
AD	5,736,759	04/98	Haushaalter			
AE	5,976,990	11/99	Mercaldi et al.			
AF	5,989,927	11/99	Yamonobe			
AG	6,101,085	08/00	Kawahara et al.			
AH	6,215,650	04/01	Gnade et al.			
AI	6,258,654	07/01	Gocho			
AJ	6,287,935	09/01	Coursey			
AK	6,325,017 B1	12/01	DeBoer et al.			
AL	6,335,049 B1	01/02	Basceri			

## FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM	JP 04-24922	01/92	Japan - Mitsubishi			X	
AN	JP 04-115533	04/92	Japan - Oki Elec.			X	
AO	JP 04-180566	06/92	Japan - Mitsushita			ABS	
AP	JP 08-060347	03/96	Japan - Fujitsu			X	
AQ	EP 0 810 666 A1	12/97	EPO - Oki Electric			N/A	

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

AR		
AS		
AT		

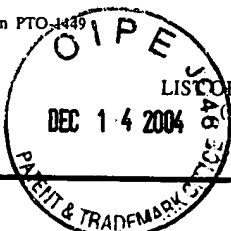
EXAMINER

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10/086,942LIST OF ART CITED BY APPLICANT  
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## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,566,147 B2	05/03	Basceri et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM	EP 0 892 426 A2	01/99	EPO - Ramtron			N/A	
	AN	WO 01/16395	03/01	WIPO - Micron			N/A	
	AO							
	AP							
	AQ							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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	AS		
	AT		

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